P-11

Chris Guarino Living Notes

Operations Procedure

Steps:

1. Insert Wafer
   1. Pay attention to notch orientation.
2. Turn on Vacuum
3. Click Manual Load
4. Focus Tool
5. Drive to the Scan Site
   1. Center of the feature to be measured.
   2. Pay close attention to any debris that may interfere with site scan.
6. Set Scan Length
   1. Blue Arrow, Leave a 200 A field length on either site of feature.
7. Start
   1. Confirm scan speed is set to 50.
8. Level Scan
   1. Set scale to (3500,-3500) This is good for visibility of the scan.
   2. Scale options under View/z Graph
9. Print Results
   1. Write LOT name & Process
10. Unload by using Manual Load. It will reset the stage.

Record like:

Ex:

|  |  |  |  |
| --- | --- | --- | --- |
| Wafer | Center | Mid | Edge |
| # |  |  |  |

NOTE:

* Disregard any site comments. Go by the Mask/Site reference.
* Keep in mind you can use where you position your cursor when measuring and along your measurement line to find the up or down areas you w=are looking to measure in the cross section.
* Anything that measures -50 to 50 Angstroms is considered PLANAR